

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of
Applicants : Zheng et al.
Serial No. : 10/790,492
Filed : March 1, 2004
Title: : **ATOMIC LAYER DEPOSITION OF CAPACITOR DIELECTRIC**
Docket No. : MIO 0082 N2/40509.292
Examiner : Thomas, Toniae M.
Art Unit : 2822
Conf. No. : 9512

MAIL STOP AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

EFS Web Electronic Submission
April 6, 2006

Sir or Madam:

AMENDMENT AFTER FINAL

This paper is being filed in response to the Office Action mailed January 10, 2006 and the subsequent Advisory Action of March 1, 2006. Reconsideration of the present application is respectfully requested in light of the amendments and remarks below, which include, in order of appearance, beginning on separate sheets:

- Amendments to the Claims; and
- Remarks.